

# SIHI® Dry PD Mi Series Single-stage, dry-running vacuum pumps for process applications

Models Mi450 and Mi650



### Deep vacuum in a clean, dry-running design

SIHI® Dry PD Mi Series vacuum pumps were specifically developed for use in chemical, pharmaceutical and other process applications requiring deep vacuum. Unlike conventional twin-screw vacuum pumps, SIHI Dry PD Mi Series pumps do not require fluids for sealing or lubricating. Their dry-running design eliminates fluid acquisition and disposal costs while allowing uncontaminated solvent and process vapors to be recovered downstream. Moreover, their advanced design can help reduce the time required to achieve target vacuum levels, improving throughput times and process efficiencies.

#### **Benefits**

- High reliability, even under harsh process conditions, due to particle and liquid carryover possibility and safe handling of condensable, corrosive or toxic media
- **High availability** due to integrated condition monitoring with pre-failure detection and data logging
- **Minimal downtime** due to self-draining, top-down flow and simple on-site serviceability by own staff
- Low total cost of ownership due to elimination of lubrication and mechanical seals, low-maintenance costs and energy-efficient design

#### **Applications**

SIHI Dry PD Mi Series dry-running vacuum pumps are engineered to develop deep vacuum under demanding process conditions, including those in classified areas.

#### **Principle industries**

- Chemical
- Fine chemical
- Pharmaceutical

#### Key vacuum applications

- Distillation
- Drying
- Batch reactors



Figure 1: SIHI Dry Mi450 pump

#### General technical data

Parameter	Units	Mi450	Mi650
Max. suction capacity	m³/h (cfm)	450 (265)	680 (400)
Final pressure	mbar a (mtorr a)	< 0.005 (< 3.75)	< 0.001 (< 7.5)
ATEX certificate	-	€ II 2 G IIC T3 Gb	€ II 2 G IIC T2 Gb
Absorbed power at final pressure	kW (hp)	< 4 (< 5.4)	< 6 (< 8.0)
Max. backpressure	mbar g (torr g)	100 (75)	100 (75)
Gas inlet temperature	°C (°F)	0 to 100 (32 to 312)	0 to 100 (32 to 312)
Gas outlet temperature	°C (°F)	≤ 195 (T3) (≤ 383 [T3])	≤ 290 (T2) (≤ 554 [T2])
Sound pressure level <sup>1</sup>	dB (A)	< 70	< 75
System weight	kg (lb)	~400 (~882)	~400 (~882)

<sup>&</sup>lt;sup>1</sup> DIN ISO 9614 / 21680

#### **Electrical data**

Parameter		Mi450	Mi650
Power connection	-	L1, L2, L3, PE (without N)	
Voltage	VAC	400 to 500 ± 10%	
Frequency	Hz	47 to 63	
Protection	-	IP54	
Max. power consumption	kW (hp)	12.5 (16.8)	
Pre-fuse (three-pole)	А	3	2

#### Purge gas

Parameter		Mi450	Mi650
Medium	-	N <sub>2</sub> (air, CO <sub>2</sub> )	
Gas quality		Min. CLASS 2.4.1 (according to ISO 8573-1:2010)	
Purge gas consumption (in operation)	NI/min (SCFM)	20 (0.71)	
Pressure	barg (psig)	3 to 8 (43 to 116)	

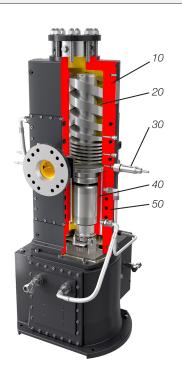
#### **Cooling water**

Parameter		Mi450	Mi650
Medium	-	water, conductivity > 50 μS (demineralized water on request)	
Medium temperature	°C (°F)	15 to 40 (59 to 104)	
Max. admissible static medium pressure	barg (psig)	6 (87)	
Min. flow rate	l/min (gpm)	7 (1.85)	

#### Material design

Wetted parts, process and coolant media sides

Parameter	Item number	Mi450	Mi650
Casing	10	EN-GJS-4	400-18-LT
Twin screws	20	EN-GJS	5-500-14
Cooling circuit	30		blated, EPDM, S, 1.0976
Bearing cartridge	40	1.4021	
Motor casing	50	EN-GJL-250	
Suction strainer (not shown)		Stainless s	steel/PTFE



#### Features and benefits

#### **Built for harsh processes**

# Tolerates particle and liquid carryover without any suction side filter

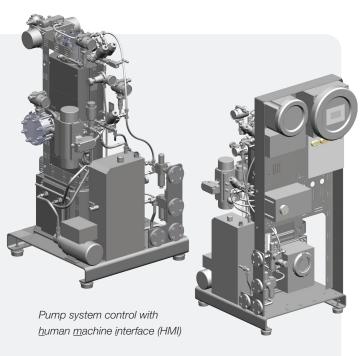
- Top-down flow avoids particle deposits inside of the pump
- No wear caused by particle carryover due to contactfree principle
- Optional integrated liquid cleaning by flushing module
- Particle carryover and pump drying by optional integrated gas flushing module

#### Handling of condensable and corrosive media

- Prevention of condensation inside of the pump by optional integrated gas dilution module
- Optional integrated liquid cleaning by flushing module
- Reduction of condensation by temperaturecontrolled operation

#### Safe handling of toxic media

- Hermetical, tight execution
- Pump internal secondary cooling loop, decoupled from customer cooling water



#### Improved product quality

#### High pumping performance

- Remarkably high pump speed at low pressure allows higher flow rate of process gases
- · Lower final pressure

#### Zero process contamination

- Truly dry and contact-free principle free of any service liquids
- Absolutely free of gear oil due to electronically synchronized shafts

#### **Engineered for easy system integration**

#### **Certified explosion protection**

- ATEX-certified, even without flame arrester in Category 2 systems
- No source of ignition due to consequential contactfree operation

#### **Customized vacuum system solutions**

• Pre-engineered modules match all individual process needs

#### No pressure control valve necessary

• Adjustable suction capacity due to variable rotational speed

#### An integrated solution

- Pre-engineered modules are completely mounted and tested
- Small-footprint design saves useful space

#### No PLC control

- Self-controlled, pre-engineered modules
- Local control via human machine interface (HMI) panel
- Data access via Ethernet

#### **Easy communication**

- Availability of bus standards as well as I/O interface
- Equipped with HMI

#### Fast installation and startup

#### Self-controlled vacuum system

 Completely assembled, wired, tested and self-controlled vacuum system allows easiest commissioning

### Lower maintenance costs and downtime

# No oil checks, exchanges and disposals required

- Free of oil as service liquid
- No gear oil

#### No wearing

- Consequent contact-free principle
- Long-life bearings
- Contact-free sealings

#### Continuous condition analysis

- Data logging
- Online monitoring of pump status
- Simple failure codes

#### Easy to clean and service

#### Only cleaning on demand

- Condition monitoring by independent data record of both shafts
- Pre-failure detection

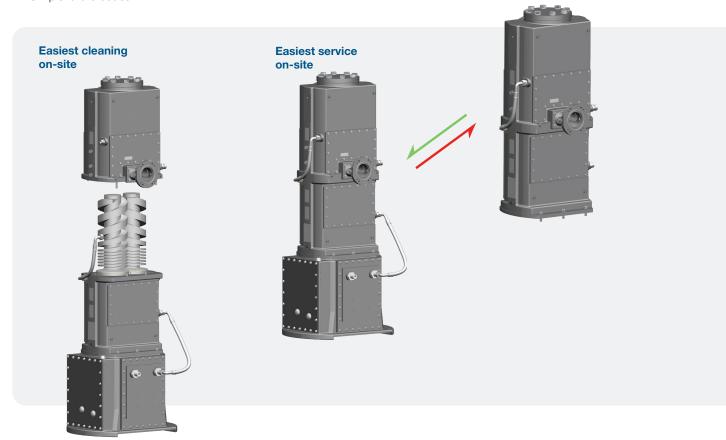
#### Designed for in situ cleaning and on-site service

- Easy dismantling of the pump casing without bearing removal
- No high-tech workshop required
- Can be done on-site by own staff
- Independency on third party service

#### **Lower operating costs**

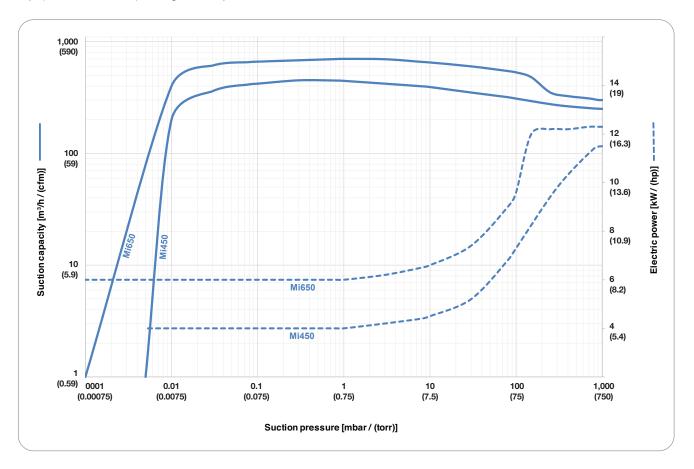
#### Low power consumption

- High-tech screws' design optimized for highest efficiency
- Frequency control allows to improve energy-efficient operation by operator



### Suction capacity curves

Operating points below the characteristic curve are achievable by speed variation, depending on the system execution.



The operating data is valid under following conditions:

- Process media: Dry air 20°C (68°F)
- Cooling media inlet: Water 25°C (77°F)
- Discharge pressure: 1,013 mbar (760 torr) atmospheric pressure
- The suction volume is related to the pressure at the suction nozzle.

Tolerance on operating data is  $\pm$  10%.

# **Pre-engineered systems**

SIHI Dry PD Mi Series pumps are available in cost-effective standard packages to ensure peak performance and minimize engineering delays. These fully tested and documented pre-engineered systems enable you to deploy a completely new system quickly or upgrade an existing one.

Madalas		Pre-engineered systems		
	Modules	Standard	Configured	Premium
Vacuum pump	SIHI Dry Mi450 or Mi650	X	X	X
Osmbool	Control FX	Х	X	
Control	Control Profibus DP		Standard Configured  X X	X
Commbo omit	Supply unit			X
Supply unit	Protective motor switch			X
Purge gas	Purge gas system	X	X	X
Base frame	Base frame		X	Х
Dase Iraille	Rack			Х
Cooling	Direct cooling without flanges	X		
Occining	Secondary cooling circuit		X	X
Shut-off valve suction	Butterfly valve		×	X
Flushing	Threaded		X	X
Gas dilution	Standard		X	X
Shut-off valve discharge	Butterfly valve		X	X
	Evaluated Pt100 sensor in cooling jacket	Х	X	Х
	Evaluated Pt100 sensor on discharge side		X	X
Sensors	Evaluated Pt100 sensor on suction side			X
	Evaluated pressure-side pressure transmitter	X	X	X
	Evaluated suction-side pressure transmitter		X	X

### Pre-engineered systems — Standard

This system configuration provides basic equipment for the operation of the vacuum pump. The scope of supply includes the following components:

Modules		Description
Vacuum pump	SIHI Dry Mi450 or Mi650	<ul><li>Pump</li><li>Suction sieve</li><li>Integrated motors</li><li>Integrated drive control</li></ul>
Control	Control FX	SIHI Control FX fixed-sequence control with sensor evaluation     Integrated communication interface
Purge gas	Purge gas system	Purge gas control unit Ex-p
Cooling	Direct cooling without flanges	The connection to customer's coolant system is directly connected to the pump. A strainer is installed in order to protect the pump.
Sensors	Thermometer pressure transmitter	<ul> <li>Evaluated Pt100 sensor in cooling jacket</li> <li>Evaluated pressure-side pressure transmitter</li> </ul>

### Available communication interfaces:

#### I/O interface

• Digital I/O

Ex - p Release / Start / Stop / Reset / Operation / Failure / Warning

• Analog I/O

Set value speed / Vital status / Current speed value

#### **Bus** - Communication

- CANopen Slave ISO11898
- Pump control (see I/O)
- Display of operation mode

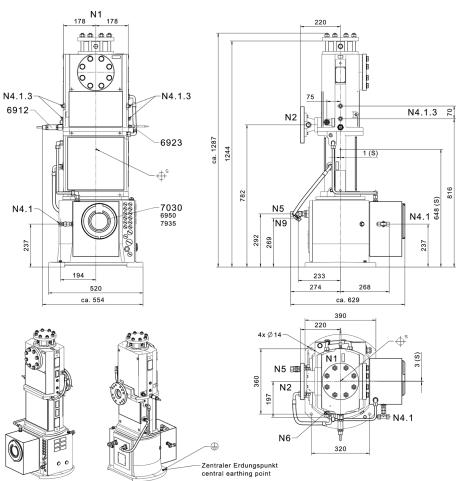
#### Bluetooth® - Communication

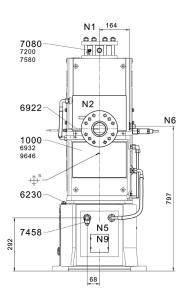
 On-site operation via tablet-PC, SIHI BT remote app via Bluetooth communication and vacuum pump integrated SIHI Control FX sequence control



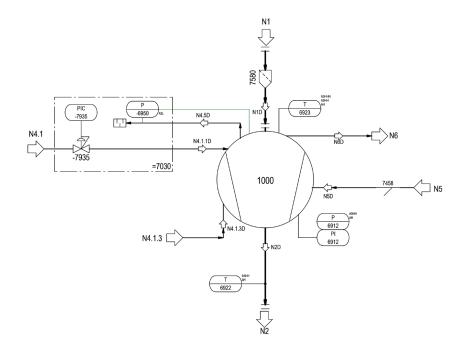
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#### **Dimensions (mm)**









### Pre-engineered systems—Configured

This system configuration provides an extended basic equipment for the operation of the vacuum pump. The scope of supply includes the following components:

Modules		Description
Vacuum pump	SIHI Dry Mi450 or Mi650	<ul><li>Pump</li><li>Suction sieve</li><li>Integrated motors</li><li>Integrated drive control</li></ul>
Control	Control FX	<ul> <li>SIHI Control FX fixed-sequence control with sensor evaluation and control sequences such as Start, Stop, Warm up, Standby, Vacuum, Cleaning and Failure</li> <li>Integrated communication interface</li> </ul>
Purge gas	Purge gas system	Purge gas control unit Ex-p
Base frame	Base frame	Base frame with machine feet
Cooling	Secondary cooling	Secondary cooling circuit with cooling pump
Shut-off valve suction	Butterfly valve	Controlled, suction shut-off valve
Flushing	Threaded	Controlled N <sub>2</sub> flush and cleaning valve
Gas dilution	Standard	Controlled gas dilution module
Shut-off valve discharge	Butterfly valve	Controlled discharge shut-off valve
Sensors	Thermometer pressure transmitter	<ul> <li>Evaluated Pt100 sensor in cooling jacket</li> <li>Evaluated Pt100 sensor in discharge side</li> <li>Evaluated pressure-side pressure transmitter</li> <li>Suction-side pressure transmitter</li> </ul>

# Available communication interfaces:

#### I/O interface

• Digital I/O

Ex – p Release / Start / Stop / Reset / Operation / Failure / Warning

• Analog I/O

Set value speed /

Vital status /

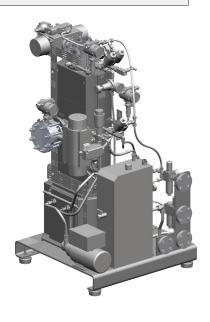
Current speed value

#### **Bus - Communication**

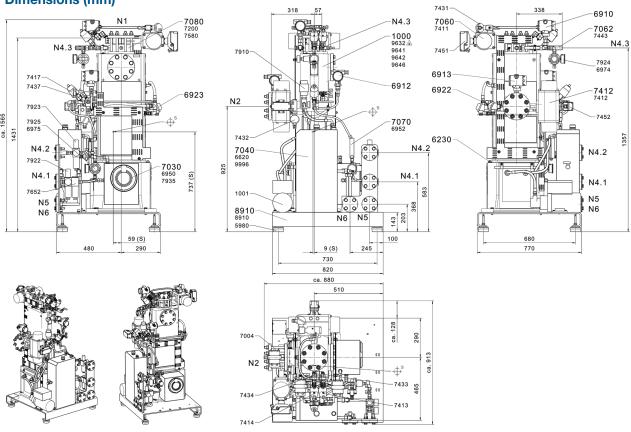
- CANopen Slave ISO11898
- Pump control (see I/O)
- Display of operation mode

#### **Bluetooth - Communication**

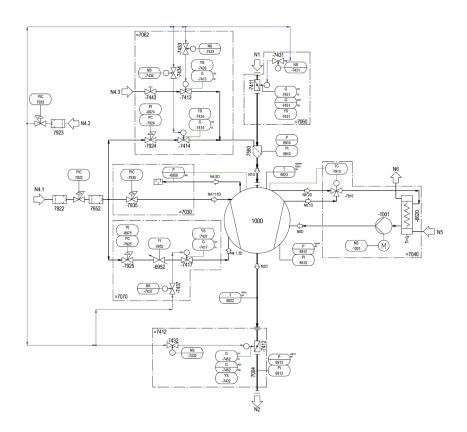
 On-site operation via tablet-PC, SIHI BT remote app via Bluetooth communication and vacuum pump integrated SIHI Control FX sequence control



#### **Dimensions (mm)**



#### P&ID



### Pre-engineered systems—Premium

In addition to the extended basic equipment, this system configuration includes a supply and control unit with HMI display. This allows convenient on-site operation and visualization of the vacuum pump status. The scope of supply includes the following components:

Modules		Description
Vacuum pump	SIHI Dry Mi450 or Mi650	<ul><li>Pump</li><li>Integrated motors</li><li>Suction sieve</li><li>Integrated drive control</li></ul>
Control	Control Profibus DP	<ul> <li>Standard control with sequence control and sensor evaluation</li> <li>Programmable sequence control with different operation modes such as Start, Stop, Warm up, Standby, Vacuum, Injection Cleaning, Post Run and Failure</li> <li>Variable control parameters such as: Warm up Temperature / Flush Drying Time / Standby Speed</li> <li>Integrated communication interface</li> </ul>
Supply unit / operation	Supply unit Protective motor switch	<ul> <li>Plug-in solution with integrated transformer for 24 VDC control voltage generation to supply:</li> <li>Display control unit</li> <li>SIHI Dry power supply switch (Ex-p)</li> <li>Cooling pump motor overload switch</li> </ul>
Purge gas	Purge gas system	Purge gas control unit Ex-p
Base frame	Base frame rack	Frame for supply unit, control unit and motor overload switch     Base frame with machine feet
Cooling	Secondary cooling circuit	Secondary cooling circuit with cooling pump
Shut-off valve suction	Butterfly valve	Controlled, suction shut-off valve
Flushing	Threaded	<ul> <li>Controlled N<sub>2</sub> flush and cleaning valve</li> </ul>
Gas dilution	Standard	Controlled gas dilution module
Shut-off valve discharge	Butterfly valve	Controlled discharge shut-off valve
Sensors	Thermometer pressure transmitter	<ul> <li>Evaluated Pt100 sensor in cooling jacket, suction and discharge side</li> <li>Evaluated pressure-side pressure transmitter</li> <li>Evaluated suction-side pressure transmitter</li> </ul>

# Pump system control with HMI display (control unit) and sequence control

- Programmed standard control with control sequences such as Start, Stop, Warm up, Standby, Vacuum, Injection Cleaning, Post Run and Failure
- Dirt detection
- Identification bearing lifetime end
- Detailed display of operation mode
- Programmable performance field

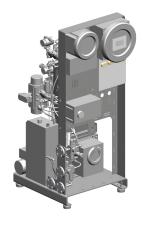
### Communication interfaces

#### **Bus** - Communication

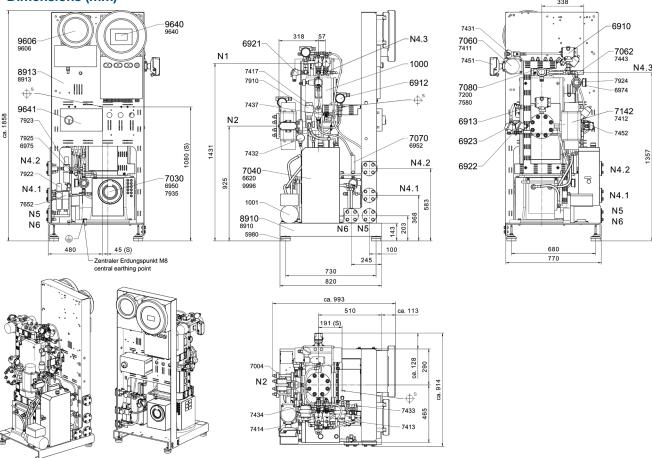
- Profibus DP (IEC 61158)
- Pump control (see control)
- Display of operation mode

#### On-site display

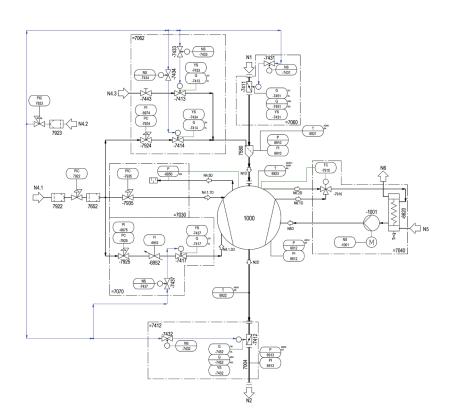
- Visualisation
- On-site operation
- Data logger



#### **Dimensions (mm)**



#### P&ID



# **Standard modules for specific applications**

SIHI Dry Mi Series vacuum pump systems can be configured from pre-engineered modules to meet exact system requirements.

Numerous modules are available.

Vacuum pump	Execution	Features
SIHI Dry Mi450 or Mi650		
	Pump Suction strainer Integrated motors Integrated drive control	Two screw-shaped displacing bodies rotating in opposite directions without contact

Control	Execution	Features	
Basic	<ul> <li>Integrated in pump</li> <li>Control of internal temperature</li> <li>Control of torque</li> <li>Electronical overload protection</li> <li>On-site operation via tablet-PC, SIHI BT remote app via Bluetooth communication</li> </ul>	Operations: Status messages: No valve control No sensor evaluation	Start, stop Failure signal
Dynamic  Characteristic:	Like control variant <b>Basic</b> , additionally:  • Variable speed via integrated frequency converter	Operations:  Status messages:  No valve control  No sensor evaluation	Start, stop, variable speed Failure signal
SiHi Control Fx  Characteristic:  Sequence chart:  Ready to start Start bereit Nachspülen Stopp Rotor diagnose Rotor diagnose Vacuum request Vakuum Androderung Vakuum Betrieb	Like control variant <b>Dynamic</b> , additionally:  On-site operation via tablet-PC, SIHI BT remote app via Bluetooth communication and vacuum pump integrated SIHI Control FX sequence control  Fixed parameter  Data logger  Detailed status messages  Control of internal temperature  Control of torques  Electronical overload protection  Integrated pressure controller  Programmed valve control (for all standard valves)  Input for digital signals  Digital status messages	Communication: Operations:  Speed set value: Display of operation, modes such as:  Valve control: • Valve, suction side • Valve, discharge side • Gas dilution • Cleaning (liquid flushin) • Gas flushing (N₂ flushin) • Gas flushing (N₂ flushin) • Limit switch, suction side • Limit switch, suction side • Limit switch, discharg • Pressure transmitter • Temperature sensors  Digital inputs:  Digital status messages:	ing) side valve

Control	Execution	Features		
Control Profibus DP	Control and supply unit mounted directly on the vacuum system	Housing:	Coated aluminium/ polyester resin	
	On-site operation via HMI	Communication:	via Profibus DP (IEC 61158)	
	<ul> <li>Variable parameters for process optimizing as: Pre-run, flushing, post-run timers</li> </ul>	Operations:	Start, stop, vacuum, cleaning, post run	
	Data logger	Speed set values:	Digital, via Profibus	
SALURIAN CO	Ethernet connection for additional monitoring respectively, connection of modem for remote maintenance	Display of operation modes such as:	, No Failure, Operation Warning, Failure,	
Characteristic:	Detailed status messages		Failure messages, etc.	
s	Control of internal temperature	Valve control:     Valve. suction side		
1	Control of torques	Valve, discharge sid	le	
↓	Gas dilution     Electronical overload protection     Cleaning (lic		d flushing)	
Sequence chart:	Integrated pressure control	Gas flushing (N₂ flushing)  Sensor evaluations:		
Ready to start Gas flushing				
Startbereit Nachspülen Stop	Programmed valve control (for standard valves)	<ul><li>Limit switch, suction</li><li>Limit switch, discha</li></ul>		
Rotor diagnosis Rotor diagnose	Input for digital signals	Pressure transmitte	o .	
Warm Up Stand By Reinigen	Digital status messages	Temperature sensor	rs	
Warm Fahren Stand by Cleaning Vacuum request Vakuum Anforderung	Cooling pump control (including post-run)	Digital inputs:	Start, Stop, Vacuum, Cleaning, Tmin (Warm up),	
Vacuum Antoreerung Vacuum Detrieb Vakuum Betrieb	Cooling pump status message via bus available		Cleating, 1 min (warm up),  X <sub>max</sub> (Maximum value evaluation for temperature and pressure)	
		Digital status messages:	No Failure, Operation, Warning, Failure, Vacuum, Cleaning	

Supply unit / operation	Execution	Features	
Supply unit	Plug-in solution with integrated transformer for 24 VDC control voltage generation for display control unit  SIHI Dry – Ex-p circuit switch (separation of SIHI Dry supply voltage	Housing:	Coated aluminium/ polyester resin
P	<ul> <li>and communication line with contactors)</li> <li>Wired and mounted on common baseplate</li> <li>Main switch (lockable)</li> <li>Installation of SIHI Dry and supply unit in Ex-zone 1</li> </ul>	Frequency: Voltage:	50 Hz 3 x 400 – 500 VAC, PE
Protective motor switch	Coolant pump is controlled via control unit (9X) started and stopped     Motor overload switch (externally accessible)	Housing:  Electrical connect Frequency:	Coated aluminium/ polyester resin tion: 50 Hz
		Voltage:	3 x 400 – 500 VAC, PE

Purge gas	Execution	Features	
Purge gas system	Motor and electronics of SIHI Dry are kept under overpressure with shielding gas. It permits pump installation within a hazardous area.	Housing:	Stainless steel
	The purge gas system controls the necessary operating conditions.	Connection:	DN12 pipe fitting

Base frame	Execution	Features
Base frame	Pump (and if applicable, the emission condenser) are mounted together on a base frame with four machine feet.	
Rack	Additionally to base frame: Rack assembly for supply unit and control unit	

Cooling	Execution	Features
Direct cooling without flanges	The connection to customer's coolant system is directly connected to the pump. A strainer is installed in order to protect the pump.	Material execution: service side: 1.4408/brass  Cooling water connections: 2 x G ½ in
Direct cooling	The connection to customer's coolant system is realized with flanges (requires base frame).	Material execution: service side pipe/fittings: 1.4571/NBR  Cooling water connections: 2 x DN25 PN40
Direct cooling with thermostatic valve	Additionally to direct cooling:  A temperature controller is installed to adapt the current demand of customer's coolant.	Like direct cooling, additionally:  Material execution: service side thermostatic valve: Brass

Cooling	Execution	Features	
Secondary cooling circuit	Closed cooling loop for SIHI Dry Internal secondary cooling loop is decoupled from customer side cooling water Protection against contamination and calcification Homogeneous tempered SIHI Dry via temperature controller	Material execution Cooling loop: Pipe / fittings: Cooling water connections: Electrical connecti Frequency: Voltage: or	1.4571 1.4571 2x DN25 PN40
Secondary cooling with thermostatic valve	Additionally to secondary cooling circuit:  A temperature controller is installed to adapt the current demand of customer's coolant.	Like D/Q, additional Material execution Valve: Voltage:	service side thermostatic  1.4581  3 × 400 VAC, PE  3 × 500 VAC, PE

Shut-off valve, suction side	Execution	Features
Butterfly valve	Isolation of the vacuum pump from the reactor:     Entry of medium into the working chamber after process is prevented     Backflow through the pump and resulting ventilation of the reactor are avoided.	Scope of supply:  Valve, PFA/PTFE conductive lined  Drive, designed for control pressure of 3 to 6 barg (43 to 87 psig), closed by spring energy  Solenoid valve  Limit switch

Gas and liquid flushing	Execution	Features
Flanged	The gas flushing using inert gas allows drying or also the discharge of residual gases from the work chamber. In addition, a liquid flush can remove particles or deposits.  The flushing can be activated by a cleaning request, post-run or injection flushing.	Scope of supply:  • 2/2-ways-valve, DN25, stainless steel / PTFE with drive, designed for control pressure of 3 to 6 barg (43 to 87 psig), closed by spring energy  • Solenoid valve  • Pressure reducer  • Needle valve
Threaded	Like above, but threaded connections instead of flange connections.	Scope of supply:  • 2/2-ways-valve, G ½ in, stainless steel / PTFE with drive, designed for control pressure of 3 to 6 barg (43 to 87 psig), closed by spring energy  • Solenoid valve  • Pressure reducer  • Needle valve, stainless steel

Connection, suction side	Execution	Features
Adapter	Adapter for installation of sensors and/or flushing valves on suction side for systems with flame arresters.	Material execution: Stainless steel 1.4571

Gas dilution	Execution	Features
Standard	To minimize deposits and corrosion, dry inert gas (e.g., nitrogen) is injected into the working space of the SIHI Dry pump.	Scope of supply:  2/2-ways-valve, G ½ in, stainless steel / PTFE with drive, designed for control pressure of 3 to 6 barg (43 to 87 psig), closed by spring energy  Solenoid valve  Flow indicator (430 to 4,300 Nl/h, 15.2 to 152 SCFM) with needle valve  Pressure reducer
Extended	To minimize deposits and corrosion, dry inert gas (e.g., nitrogen) is injected into the working space of the SIHI Dry pump.	Scope of supply:  • 2x 2/2-ways-valve, G ½ in, stainless steel / PTFE with drive, designed for control pressure of 3 to 6 barg (43 to 87 psig), closed by spring energy  • 2 solenoid valves  • 2 flow indicators (430 to 4,300 NI/h, 15.2 to 152 SCFM) with needle valve  • Pressure reducer

Shut-off valve, cooling discharge side	Execution	Features
Butterfly valve	Isolation of the vacuum pump from the exhaust line.  The pump will be decoupled from the vent system and is protected from condensable media during standstill.	<ul> <li>Scope of supply:</li> <li>Valve, PFA/PTFE, conductive lined</li> <li>Drive designed for control pressure of 3 to 6 barg (43 to 87 psig), closed by spring energy</li> <li>Solenoid valve</li> <li>Limit switch</li> </ul>
Discharge condenser	Discharge condenser for condensation of vapors.	Type:  Plate and shell – condenser  Exchange area 1.7 m²  Material execution (product / service side): Stainless steel / stainless steel or Stainless steel / steel  Connections:  Process side: DN50/PN16 Service side: DN25/PN16

Connection, discharge side	Execution	Features
Transition pipe	For connection of components on the discharge side, i.e., discharge condenser.	Material execution: Stainless steel  Connections:  Inlet: DN40/PN16
		Outlet: DN50/PN16

Sensors	Execution	
Resistance thermometer	Resistance thermometer (Pt100) for measuring temperature on suction side <b>and/or</b> Resistance thermometer (Pt100) for measuring coolant temperature <b>and/or</b> Resistance thermometer (Pt100) for measuring temperature on discharge side	
Pressure transmitter	Pressure transmitter for measuring of suction pressure <b>and/or</b> Pressure transmitter for measuring dynamic pressure or exhaust pressure	

Accessories	Execution	Feature
Tablet	Tablet or computer for control of the pump via Bluetooth for control executions: BASIC, DYNAMIC, CONTROL FX. Suitable for use in potentially explosive atmospheres.	<b>Display size:</b> 8 in



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PUTB000142 (EN/A4) April 2020

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